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*Innovations through new Ceramic Materials and Processes:* 

When Innovations meet Market Needs

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## Outline

### Colloid chemistry

- Manipulation of colloidal particles
- Enzyme assisted coagulation of suspensions: Direct Coagulation Casting, DCC<sup>®</sup>
- Ceramic foams and emulsions
- Capillary filling: μ sensor array
- Chemical micro-reactor
- Processing properties of HTSC materials for fault current limiters
- Rapid prototyping of ceramics: Cercon<sup>®</sup>
- Summary



## Why Colloidal Processing of Ceramics?



## Shaping ceramics



Spray drying



Robocasting http://www.sandia.gov/LabN ews/LNo1-29-99/images/lens\_pix.gif



Tape casting



### Extrusion



Ferro - 'KeraJet' http://www.xaar.co.uk/industrial.htm



Pressure slip casting http://www.dorst.de/dorst\_seite/index.html



 $SiO_{2;}d_{50}=0.9 \ \mu m$ 



Ceramic components for hip joint endoprostheses <u>http://www.ceramtec.de</u>



## Concentrated Particle Gels

• Food technology



• Paper



• Paint

• Minin

•Building

material





### • Pharmaceutical



• Ceramics





http://ceramics.ethatarth Science



Small particles stick to each other and form agglomerates = large defects in the material.





### gravitational potential:

$$V_g = \frac{Gm_1m_2}{r}$$

### Van der Waals potential:

$$V_{\rm vdW} = -\frac{A}{6} \left( \frac{2}{s^2 - 4} + \frac{2}{s^2} + \ln \frac{s^2 - 4}{s^2} \right)$$
$$s = \frac{2a + h}{a}$$

### electrostatic interaction:

 $V_{\text{elect}} = 2\pi\varepsilon_{\text{r}}\varepsilon_{0}a\Psi_{0}^{2}\ln[1 + \exp(-\kappa h)]$  $\kappa a \text{ is sufficiently large (>10)}$ 

$$V_{\text{elect}} = 2\pi\varepsilon_{\text{r}}\varepsilon_{0}a\Psi_{0}^{2}\exp(-\kappa h)$$
(\kappa a < 5)

 $\mathbf{\kappa} = \begin{pmatrix} F^2 \sum N_i z_i^2 \\ \frac{i}{\varepsilon_r \varepsilon_0 kT} \end{pmatrix}$ 

http://ceramics.e 
$$\kappa = \left( -\frac{1}{2} \right)$$

## Why Colloidal Processing of Ceramics?





- K<sub>c</sub> critical stress intensity factor
- $\gamma$  surface energy
- a size of largest flaw in the part







m= Weibull paramter= a measure of the distribution width.

microstructural defect in sintered Al<sub>2</sub>O<sub>3</sub>

The load bearing capacity of ceramics is determined by the largest defect in the part. The largest flaw in a component can be from ~300 $\mu$  to 0.1  $\mu$ .  $\rightarrow$  Ceramics are unreliable!!

### Classical Processing of Ceramics versus colloidal processing







Enzyme Catalysis of Ceramic Forming: Direct Coagulation Casting: DCC



Materials

## Complex shaped ceramic componets via DCC











Мa

### H<sub>2</sub>O foam lamella stabilized by surface modified particles







## Foams & emulsions, ceramics





Gonzenbach, Unite Weekamics.ett 2.64 published

## Micromolding in Capillaries (MIMIC)





Capillary forces draw aqueous suspensions into microchannels.

The PDMS (poly-dimethylsiloxane) stamp is oxygen plasma-treated to make its surface hydrophilic.

Y. Xia, G. M. Whitesides, Angew. Chem. Int. Ed. 1998, 37, 550-575



## SnO2 sensor lines made by MIMIC: Directly observed

Heule, Vuillemin, Gauckler, Adv. Mater.15, 1237-1245; 2003,





33%vol suspension 6 g water, 21 g SnO<sub>2</sub> tuned by colloidal chem.

 $\begin{array}{c} \text{channel width 10 } \mu m. \\ \text{http://ceramics.ethz.ch} \end{array}$ 



### Micro-Ceramic Sensor Array M. Heule and L. J. Gauckler, Adv. Mater., 13 [23] 1790–3, (2001).



Excern mit acetor, gesintert, 250x

SnO<sub>2</sub> lines on Si with Pt microcontacts





sensor array on micro-hotplate







## Analog/Digital Microhotplate System





Andreas Hierlemann



## Chemical micro - reactor



3µm

M. Heule, K. Rezwan, L. Cavalli, L. J. Gauckler, *Adv. Mat.* 15 (14), 1191-1194, 2003

http://ceramics.ethz.ch

600n

Materials

### HTSC materials for fault current limiters



## Perovskite ABO<sub>3</sub>

K. Kamata, T. Nakamura and T. Sata, Bull. Tokyo Inst. Tech. 120, 73-79 (1974)



**R. Roy**: J. Am. Ceram. Soc. 60, 7-8, **1977**, 350-363

.....Very little cut-and-try is now needed by the molecular engineer **designing a new perovskite catalyst or superconductor** or one most likely to undergo a metal-insulator transition. (Obviously, these would sit on the borderline in the SFM.) ......

A. Müller & G. Bednorz: G. Bednorz and K. A. Müller, Z. Phys. B: Condens. Matter 64, 189,1986

Discovery of superconductivity in 1986 in La-Ba-Cu-O

## HTSC materials & potential applications



**Research:** Accelerator

**Medicine:** MRI





**Transportation:** Maglev

### **Electronics:** Microwave filters





## Pinning & weak links





http://ceramics.ethz.ch

D. Schneider, Dissertation, ETH-Zurich

## Principles of Fault Current Limiters





### **HTC Device Fabrication Technologies**

#### for Bi-2223: powder in tube, draw & redraw &annealing



#### for Bi-2212: melt processing



#### Polycrystalline Ni-based alloy

Biaxially aligned YBCO film (Pulsed-Laser-Deposition)

cs.ethz.ch

c-axis

a,b-axis



#### **Bi-2212 Phase Formation**







T<sub>q</sub>=865°C



Bi-2212 on Ag pO<sub>2</sub>=1 atm





### fully processed (SEM)

D. Buhl, T. Lang, L. J. Gauckler, Supercond. Sci. Technol. 10 (1997) 32

t

## SCFCL composite based on Bi 2212



## Fault Current Limiters (FLC)



1998 inductive FLC 1.2 MW



![](_page_27_Picture_4.jpeg)

2004 resistive FLC 20 MW

![](_page_27_Picture_6.jpeg)

![](_page_27_Figure_7.jpeg)

11(10.// 001011100.0(112.0)1

![](_page_27_Picture_8.jpeg)

![](_page_28_Picture_0.jpeg)

## SCFCL Project in ABB

- 1986 Discovery of HTS
- 1989 Start of project
- 1993 0.1 MVA "inductive" model (wr)
- 1996 1.2 MVA "inductive" model (wr)
- 1998 1.6 MVA "resistive" model (wr)
- 2001 6.4 MVA "resistive" model (wr)
- 2003 20 MVA Pilot at customer site

![](_page_28_Picture_9.jpeg)

1.6 MVA

0.02 MVA

![](_page_28_Picture_12.jpeg)

CHCRC.V4 MkC 06.09.01

© 2000 ABB Corporate Research Ltd, Baden, Switzerland

![](_page_28_Picture_15.jpeg)

## Rapid Prototyping of Ceramic Components

![](_page_29_Picture_1.jpeg)

## Etruscan bridge

![](_page_30_Picture_1.jpeg)

![](_page_30_Picture_2.jpeg)

(600 BC)

![](_page_31_Picture_0.jpeg)

![](_page_31_Picture_1.jpeg)

# Maxiumum load on a bridge during mastication

![](_page_32_Picture_1.jpeg)

![](_page_32_Picture_2.jpeg)

![](_page_32_Picture_3.jpeg)

### *Ceramic materials in dentistry*

![](_page_33_Figure_1.jpeg)

### ETH Zürich aproach: CERCON®

![](_page_34_Picture_1.jpeg)

![](_page_34_Picture_2.jpeg)

![](_page_35_Picture_0.jpeg)

## cercon brain

![](_page_35_Picture_2.jpeg)

![](_page_35_Picture_3.jpeg)

![](_page_35_Picture_4.jpeg)

## Clinical trails at UNI Zürich since 1998

![](_page_36_Picture_1.jpeg)

![](_page_36_Picture_2.jpeg)

![](_page_36_Picture_3.jpeg)

### Innovations through New Ceramic Materials and Processing

![](_page_37_Figure_1.jpeg)

![](_page_37_Picture_2.jpeg)

## Thanks is due to:

![](_page_38_Picture_1.jpeg)

for fuding: KTI (CH) NSF (CH) ABB

for collaborations with:

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ABB (CH) Ceramtec (D) Sensirion (CH) Degudent (D) Dentsply (USA) CIBA (CH) Novartis (CH) Metoxit (CH) Treibacher (A)

![](_page_38_Picture_6.jpeg)